APR 0 4 2002

U.S. DEPARTMENT OF COMMER PATENT AND TRADEMARK OFFI

REQUESTATION EXTENSION OF TIME PURSUANT TO 37 C.F.R. § 1.136(a)

10191/1466 APR 1 5 2002

Application Number 09/581,663

Filing Date August 3, 2000

Examiner S. AHMED

Invention Title

METHOD FOR PROCESSING SILICON BY ETCHING PROCESSES

Inventor:

Volker BECKER et al.

Assistant Commissioner for Patents Washington, D.C. 20231 I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on

Date: March 27, 2002

Signature:

Jong H. Lee

Applicants respectfully request a one-month extension of time in which to respond to the office action dated December 21, 2001, for which a response period expiring on March 21, 2002 was set. The extended period expires on April 21, 2002.

The Commissioner is hereby authorized to charge payment of the 1. 37 C.F.R. § 1.136 extension fee of \$110.00 to the Deposit Account of Kenyon & Kenyon, Deposit Account number 11-0600. The office is also authorized to charge any additional fees, or credit overpayments, associated with this paper to Deposit Account 11-0600.

By:

2. A duplicate copy of this form is enclosed.

Dated: March 272002

Jong H. Lee (Reg. No. 36,197)

04/05/2002 CHGUYEN 00000030 110600 09581663

01 FC:115 110.00 CH **KENYON & KENYON**

CUSTOMER NO. 26646

PATENT TRADEMARK OFFICE

NY01 462333v1